

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Luetzen, *et al.* Docket No.: INF 2004 SP 00115 US
Serial No.: 10/721,225 Art Unit: 1792
Filed: November 26, 2003 Examiner: George A. Goudreau
For: Method and Structures for Increasing the Structure Density and the Storage
Capacitance in a Semiconductor Wafer

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Submission of Translation of Priority Document

Dear Sir:

Attached is an Accurate Translation of the certified copy of German Patent
Application No. 102 55 866.3. Per the Examiner's request, Applicant has included a
Statement of Verification with the translation.

Upon review of the originally filed translation, it appears that translation errors
may have been made. Any errors in the original translation were not made with
deceptive intent. Any differences are not substantive and do not affect the fact that the
presently claimed invention is supported by the priority filing.

Respectfully submitted,

September 18, 2008
Date

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